

<b>Notice of References Cited</b>	Application/Control No. 10/071,881	Applicant(s)/Patent Under Reexamination HOSOKAWA ET AL.	
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**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
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	C	US-			
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**FOREIGN PATENT DOCUMENTS**

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**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Danev et al, "Complex Observation in Electron Microscopy", Journal of Physical Society of Japan, vol. 70, no.3, Mar. 2001, pp. 669-702
	V	
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\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
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